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#	Paper	IF	Citations
834	Divertor parameters and divertor operation in ASDEX. <b>1984</b> , 128-129, 350-358		45
833	Trapping and reflection coefficients for deuterium in graphite at oblique incidence. <i>Applied Physics A: Solids and Surfaces</i> , <b>1984</b> , 33, 265-268		25
832	Data Compendium for Plasma-Surface Interactions. <b>1984</b> , 24, S9-S117		67
831	Amorphization and Recrystallization Processes in Monocrystalline Beta Silicon Carbide Thin Films. <b>1985</b> , 51, 395		19
830	Experimental and theoretical investigations into the origin of cross-contamination effects observed in a quadrupole-based SIMS instrument. <i>Applied Physics A: Solids and Surfaces</i> , <b>1985</b> , 38, 235-252		15
829	Computer simulation of two-component target sputtering. <i>Applied Physics A: Solids and Surfaces</i> , <b>1985</b> , 37, 95-108		102
828	Reflection of low-energy hydrogen from solids. <i>Applied Physics A: Solids and Surfaces</i> , <b>1985</b> , 38, 123-129		91
827	Charge state fractions of sputtered Ni. <b>1985</b> , 22-23, 136-144		
826	Few collisions approach for threshold sputtering. <b>1985</b> , 35, 561-571		68
825	Angular distribution of particles sputtered from Cu, Pt and Ge targets by keV Ar <sup>+</sup> ion bombardment. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1985</b> , 6, 459-465	1.2	79
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822	Computer simulation of preferential sputtering. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1985</b> , 7-8, 727-734	1.2	64
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654	Study of silver diffusion into Si(111) and SiO <sub>2</sub> at moderate temperatures. <b>1991</b> , 70, 1392-1396		35
653	Monte Carlo simulation of intermixed layer formed by ion beam enhanced deposition. <b>1991</b> , 10, 532-536		1
652	The Binary Collision Model. <b>1991</b> , 4-32		1
651	Backscattering. <b>1991</b> , 142-168		
650	Thermal Vibrations and Specific Energies. <b>1991</b> , 73-82		
649	Sputtering. <b>1991</b> , 169-218		1
648	Programs Based on the BCA Model. <b>1991</b> , 83-107		1
647	Surface and depth analysis based on sputtering. <b>1991</b> , 161-256		22
646	Calculations of the sputtering energy reflection coefficient for hydrogen plasma ion bombardment on carbon surfaces. <i>Radiation Effects and Defects in Solids</i> , <b>1991</b> , 116, 37-47	0.9	1
645	Physical and Chemical Sputtering of Multicomponent Solids. <i>Fusion Science and Technology</i> , <b>1991</b> , 19, 2076-2082		14
644	Introduction. <b>1991</b> , 1-13		16
643	Implantation model for plasma ion irradiation of a sheath bounded surface. <i>Radiation Effects and Defects in Solids</i> , <b>1991</b> , 116, 49-57	0.9	1
642	Monte carlo simulations of cascade defect distributions in thin foil and bulk irradiations using the TRIM code. <i>Radiation Effects and Defects in Solids</i> , <b>1991</b> , 117, 273-284	0.9	
641	Dependence of collisional mixing on recoil energy. <b>1991</b> , 42, 3-7		1
640	Angular distribution and escape probability of sputtered atoms. <b>1991</b> , 42, 537-542		3
639	Simple model calculation for ion-beam-enhanced deposition. <b>1991</b> , 197, 381-391		3
638	The erosion of copper by reflected sandblasting grains. <b>1991</b> , 132, 231-236		4

637	An Auger depth profile analysis of a sputtered Fe-Ti multilayer structure. <b>1991</b> , 47, 127-138		1
636	Collision cascade limit to spatial resolution in focused ion beam processes. <b>1991</b> , 51, 103-112		8
635	T-DYN Monte Carlo simulations applied to ion assisted thin film processes. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1991</b> , 59-60, 21-27	1.2	140
634	Ion beam deposited epitaxial thin silicon films. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1991</b> , 59-60, 197-202	1.2	28
633	Atomic collisions, elastic recombination, and thermal diffusion during thin-film growth from low-energy ion beams. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1991</b> , 59-60, 326-331	1.2	8
632	Ion beam induced collisional mixing of interfaces. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1991</b> , 61, 394-402	1.2	6
631	Angular distributions of sputtered carbon at oblique ion incidence on graphite targets. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1991</b> , 61, 12-20	1.2	7
630	The atomic sputtering from {111} surfaces of fcc metals. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1991</b> , 53, 270-278	1.2	9
629	Sputtering of tungsten by carbon. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1991</b> , 53, 279-284.2		58
628	Theoretical study of preferential sputtering of isotopic systems at low fluence. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1991</b> , 61, 295-301	1.2	32
627	Defect depth profiles in B <sup>+</sup> and As <sup>+</sup> implanted Si. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1991</b> , 59-60, 1041-1044	1.2	7
626	A single crystal carbon self-sputtering simulation. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1991</b> , 59-60, 1378-1382	1.2	17
625	Radiation effects of high-T <sub>c</sub> superconductors. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1991</b> , 59-60, 1447-1457	1.2	10
624	Energy distributions of constituent atoms of cluster impacts on solid surface. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1991</b> , 62, 181-190	1.2	17
623	High-resolution heavy-ion-induced X-ray satellite emission study of implanted sulfur as a probe of co-implanted oxygen in an oxide substrate. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1991</b> , 56-57, 41-44	1.2	2
622	Computer simulation of boron nitride deposition by ion-beam-assisted evaporation. <b>1991</b> , 45, 73-81		26
621	Angular distributions of sputtered atoms for low-energy nitrogen irradiation of silicon. <i>Applied Physics A: Solids and Surfaces</i> , <b>1991</b> , 53, 179-184		6
620	Ar Ion Implantation Induced T <sub>c</sub> Degradation of YBa <sub>2</sub> Cu <sub>3</sub> O <sub>7-x</sub> Thin Films. <b>1991</b> , 8, 157-160		1

619	Reflection of light ion from solid surfaces studied by Monte Carlo simulation and transport theory. <b>1991</b> , 69, 439-446	5
618	Modeling of the sp <sup>3</sup> /sp <sup>2</sup> ratio in ion beam and plasma-deposited carbon films. <b>1991</b> , 59, 2391-2393	49
617	Ion beam controllable modification of YBa <sub>2</sub> Cu <sub>3</sub> O <sub>7-x</sub> superconducting thin films. <b>1991</b> , 69, 7915-7917	13
616	Modeling of H <sub>2</sub> surface conversion sources; binary (H-Ba) and ternary (H-Cs/W) converter arrangements. <b>1991</b> , 70, 2575-2583	10
615	Plasma-generator-induced effects on the dynamics of a negative-ion surface conversion source. <b>1991</b> , 69, 3485-3493	4
614	Uniform deposition of YBa <sub>2</sub> Cu <sub>3</sub> O <sub>7</sub> films over large areas using ion-beam sputtering. <b>1991</b> , 70, 6952-6957	25
613	Long-range channelling in low energy ion implantation into silicon. <b>1991</b> , 64, 253-260	13
612	The ion-beam-induced mixing mechanism of self-tracer markers in Ni: collisional versus thermal spike mixing. <b>1992</b> , 4, L481-L486	2
611	A Semiempirical Calculation of Ion-Induced Kinetic Electron Emission Statistics. <b>1992</b> , 31, 3686-3687	3
610	Calculation of Incident Angle Dependence of Ion-Induced Kinetic Electron Emission from Aluminum. <b>1992</b> , 31, 2560-2564	1
609	Velocity distribution and yield measurements of Fe ejected from FeS <sub>2</sub> during ion bombardment. <b>1992</b> , 45, 10255-10263	6
608	Ion-induced collisional relocation of multicomponent targets. <b>1992</b> , 46, 13713-13721	9
607	Molecular-dynamics simulations of bulk and surface damage production in low-energy Cu->Cu bombardment. <b>1992</b> , 71, 5410-5418	67
606	Monte Carlo simulations of sputter atom transport in low-pressure sputtering: The effects of interaction potential, sputter distribution, and system geometry. <b>1992</b> , 72, 3064-3071	27
605	Statistical properties of sputtering from individual atomic collision cascades in solids. <b>1992</b> , 71, 3975-3980	11
604	The angular distributions of sputtered particles from nickel. <i>Radiation Effects and Defects in Solids</i> , <b>1992</b> , 124, 197-202	0.9 4
603	Deviation from a Poisson Distribution of Proton-Induced Kinetic Electron Emission Statistics from Gold. <b>1992</b> , 61, 2569-2576	2
602	Damage to Crystalline Silicon Following Implantation by Low Energy Silicon Ions. <b>1992</b> , 262, 1037	

601	Computer Simulation of Atomic Collision Processes in Solids. <b>1992</b> , 279, 3		1
600	Microstructure of Zr <sub>3</sub> Al After 2 MeV Proton Bombardment. <b>1992</b> , 279, 55		
599	Auger-electron emission from slow, highly charged ions interacting with solid Cu targets. <b>1992</b> , 45, 4653-4660	51	
598	SIMS profiling of Al/Si interfaces in the presence of oxygen in the ion source or in the analysis chamber. <b>1992</b> , 271, 641-648		4
597	Angular-resolved energy distribution of secondary ions emitted from a silicon target sputtered by a xenon ion beam. <i>Applied Physics A: Solids and Surfaces</i> , <b>1992</b> , 55, 359-363		9
596	Erosion of tungsten by self-sputtering and light ion irradiation at oblique angles of incidence. <b>1992</b> , 196-198, 569-572		6
595	Surface segregation of a low-Z element and its impact on interaction with hydrogen. <b>1992</b> , 196-198, 592-595	2	
594	Search for low-erosion carbon materials. <b>1992</b> , 191-194, 45-49		13
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592	Stress in Si <sub>1-x</sub> Ge <sub>x</sub> films prepared by ion sputtering: origin and relaxation. <b>1992</b> , 222, 180-183		5
591	Modelling of physical processes in ion lithography. <b>1992</b> , 214, 144-149		3
590	Quantitative analysis of sputtering due to ion beam bombardment of solids and biological specimens in high resolution electron microscopy. <b>1992</b> , 23, 45-64		4
589	Ar ion implantation induced electrical and structural changes in epitaxial YBa <sub>2</sub> Cu <sub>3</sub> O <sub>7-x</sub> thin films. <b>1992</b> , 199, 269-275		5
588	Si <sub>0.57</sub> Ge <sub>0.43</sub> alloy layers implanted with oxygen: sputtering yields and atomic composition depth profiles. <b>1992</b> , 12, 21-26		3
587	Ion-beam-assisted deposition and ion beam synthesis of wear resistant coatings on technical surfaces. <b>1992</b> , 51, 237-242		7
586	Scanning tunneling microscopy of surface modifications induced by UNILAC heavy-ion irradiation. <b>1992</b> , 42-44, 1345-1349		20
585	Low energy ion beam oxidation of silicon surfaces: ballistics, diffusion and chemistry. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1992</b> , 65, 79-83	1.2	12
584	Secondary ion emission from YBa <sub>2</sub> Cu <sub>3</sub> O <sub>7</sub> <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1992</b> , 65, 546-549	1.2	5

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582	Insufficiently developed collision cascades in sputtering and secondary ion emission. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1992</b> , 72, 40-44	1.2	3
581	Sputtering of solids under light-ion bombardment. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1992</b> , 72, 45-50	1.2	4
580	Radiation-induced precipitation at the alloy surface during ion bombardment. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1992</b> , 71, 148-154	1.2	4
579	Kinetics of ion beam nitridation (IBN) of Si and of MBE-grown Ge and Si <sub>0.5</sub> Ge <sub>0.5</sub> alloys: The role of ion energy, ion dose and substrate temperature. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1992</b> , 67, 301-307	1.2	19
578	Computational models in atomic collision studies. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1992</b> , 67, 373-383	1.2	21
577	On some factors limiting depth resolution during SIMS profiling. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1992</b> , 67, 495-499	1.2	35
576	An ion optical decel system for oblique angular impact of low-energy ions on targets. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1992</b> , 70, 441-444	1.2	5
575	Dynamic Monte-Carlo simulation of compositional change and atomic redistribution in multicomponent targets under ion bombardment. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1992</b> , 69, 193-199	1.2	21
574	Sputtering of a hydrogenated barium surface in a negative ion surface conversion source. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1992</b> , 69, 389-402	1.2	13
573	Influence of the interaction potential on simulated sputtering and reflection data. <b>1992</b> , 24, 171-176		20
572	Hydrogen and deuterium depth profiles in a barium surface converter determined by LAMS and P-SNMS. <b>1993</b> , 68, 265-274		1
571	Residual stress determination by X-ray diffraction in tungsten thin films. <b>1993</b> , 65-66, 99-105		5
570	Sputtering of NiTi alloys: a comparison of experiment and simulation. <b>1993</b> , 44, 209-212		8
569	An overview of the transport theory of charged particles. <b>1993</b> , 41, 673-703		20
568	Monte-Carlo study of reactive ion-beam assisted film growth. <i>Applied Physics A: Solids and Surfaces</i> , <b>1993</b> , 56, 561-565		2
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566	Isotopic fractionation in the sputtering of <sup>92</sup> Mo- <sup>100</sup> Mo targets. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1993</b> , 73, 135-150	1.2	31



565	High dose arsenic implantation of silicon. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1993</b> , 73, 352-356	1.2	2
564	Angular resolved energy distribution of secondary ions emitted from a silicon target sputtered by rare gas ions under oblique incidence. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1993</b> , 78, 294-299	1.2	12
563	Comment on Isotopic fractionation in the sputtering of $^{92}\text{Mo}$ - $^{100}\text{Mo}$ targets by D.L. Weathers, S.J. Spicklemire, T.A. Tombrello, I.D. Hutcheon and H. Gnaser. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1993</b> , 83, 329-333	1.2	14
562	Time evolution of ion slowing-down in amorphous solids. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1993</b> , 83, 345-350	1.2	10
561	Computer simulation studies of low energy B implantation into amorphous and crystalline silicon. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1993</b> , 83, 87-94	1.2	18
560	Threshold energy for sputtering and its dependence on angle of incidence. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1993</b> , 83, 95-109	1.2	60
559	Precise determination of H recoil cross sections for 1.5 MeV He ions. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1993</b> , 82, 474-480	1.2	7
558	Angular distributions of gold sputtered from a (111) crystal: Dependence of spot shapes and of spot and background yields on the primary ion mass and energy and on the target temperature. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1993</b> , 82, 220-233	1.2	22
557	Sputtering yield increase with target temperature for Ag. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1993</b> , 82, 255-258	1.2	20
556	Influence of ionization processes on radiation defect formation. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1993</b> , 80-81, 3-6	1.2	3
555	Fluence dependent concentration of low-energy Ga implanted in Si. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1993</b> , 80-81, 110-114	1.2	5
554	Atomistic simulation of the interaction of slow protons with an iron surface. <b>1993</b> , 15, 1263-1272		
553	Colloid size distributions in ion implanted glass. <b>1993</b> , 162, 217-224		60
552	The physics of ion impact cathode heating. <b>1993</b> , 74, 6534-6537		2
551	Angular distributions of sputtered zirconium atoms. <b>1993</b> , 98, 5887-5898		7
550	Low Energy Ion Implantation / Deposition as a Film Synthesis and Bonding Tool. <b>1993</b> , 316, 833		10
549	Yields and composition changes in low-energy sputtering of binary alloys: Experiments and computer simulations. <b>1993</b> , 47, 14093-14102		3
548	Damage and deuterium trapping in highly-oriented pyrolytic graphite. <b>1993</b> , 73, 2225-2233		29

547	Damage-to-dose ratio after low energy silicon ion implantation into crystalline silicon. <b>1993</b> , 8, 2305-2309		1
546	Modeling of Dopant Diffusion during Annealing of Sub-Amorphizing Implants. <b>1993</b> , 316, 197		1
545	Molecular dynamics study of sputtering of Cu (111) under Ar ion bombardment. <i>Radiation Effects and Defects in Solids</i> , <b>1994</b> , null, 251-266	0.9	47
544	Monte Carlo and other simulation codes for ion-induced radiation effects. <i>Radiation Effects and Defects in Solids</i> , <b>1994</b> , 129, 15-17	0.9	2
543	Backscattering and sputtering with the monte-carlo program TRIM.SP. <i>Radiation Effects and Defects in Solids</i> , <b>1994</b> , null, 239-250	0.9	10
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540	Monte Carlo simulation of the ion beam enhanced deposition of silicon nitride films. <b>1994</b> , 3, 690-696		
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538	Composition of thin films deposited by ion beam sputtering of a compound target: case of Y?Ba?Cu?O. <b>1994</b> , 241, 16-20		2
537	Contributions of different generations of recoils to sputtering by backscattered light ions. <b>1994</b> , 16, 75-88		5
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534	Boundary Conditions at the Vessel Walls being in Contact with a Hot Plasma. <b>1994</b> , 34, 293-299		
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532	Energy and angular distributions of sputtered particles. <b>1994</b> , 140, 1-110		166
531	A survey of the physical processes which determine the response function of silicon detectors to alpha particles. <b>1994</b> , 339, 102-108		43
530	Ballistic simulation in surface science. <b>1994</b> , 45, 733-752		3

529	Growth mode of Ge films on Si(100) substrate deposited by ion beam sputtering. <b>1994</b> , 246, 30-34		5
528	Basic physics of radiation damage production. <b>1994</b> , 216, 1-28		194
527	First-wall erosion in fusion devices. <b>1994</b> , 212-215, 97-100		5
526	Erosion processes in plasma-wall interactions. <b>1994</b> , 211, 202-214		62
525	Energy resolution of silicon detectors: approaching the physical limit. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1994</b> , 85, 642-649	1.2	68
524	Fast formulae for the time integral in binary collision calculations. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1994</b> , 84, 425-433	1.2	1
523	Materials characterisation using heavy ion elastic recoil time of flight spectrometry. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1994</b> , 94, 277-290	1.2	39
522	Ion beam annealing effects of surface amorphous layers produced by Sb implanted <100> Ni using 1.5 MeV Xe+ and Ar+ ion beams. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1994</b> , 93, 261-267	1.2	2
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520	Total sputter yield of LiF induced by hyperthermal ions measured by a quartz microbalance. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1994</b> , 90, 496-500	1.2	24
519	Monte Carlo study of incident-angle dependence of ion-induced kinetic electron emission from solids. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1994</b> , 90, 552-555	1.2	7
518	On the energy distribution of sputtered atoms at normal ion incidence. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1994</b> , 93, 415-420	1.2	8
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516	On model parameters in applications of TRIM code to ion scattering from surfaces. <i>Radiation Effects and Defects in Solids</i> , <b>1994</b> , null, 313-320	0.9	
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511	Experiments on steady state particle control in Tore Supra and DIII-D. <b>1995</b> , 220-222, 91-103		28
510	Critical test of the c-BN sputter model. <b>1995</b> , 74-75, 723-728		17
509	Transport Characteristics and Structural Analysis of YBa <sub>2</sub> Cu <sub>3</sub> O <sub>7-x</sub> Thin Films Implanted with Argon Ions. <b>1995</b> , 147, 119-128		6
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507	Surface sputtering from cold dark matter interactions: proposed search for its diurnal modulation. <b>1995</b> , 3, 37-51		5
506	Recovery of superconductivity and recrystallization of ion-damaged YBa <sub>2</sub> Cu <sub>3</sub> O <sub>7-x</sub> films after thermal annealing treatment. <b>1995</b> , 243, 294-302		16
505	The effects of oxygen annealing on transition-metal implanted single-crystal YBa <sub>2</sub> Cu <sub>3</sub> O <sub>7-x</sub> <b>1995</b> , 247, 34-42		3
504	Analysis of long term samples in Tore Supra. <b>1995</b> , 220-222, 506-510		10
503	Experiments and TRIM simulations on sputtering of well defined amorphous metal alloys containing impurities. <b>1995</b> , 220-222, 895-898		5
502	Angular distribution of rare gas atoms trapped in thin films deposited by ion beam sputtering of an YBa <sub>2</sub> Cu <sub>3</sub> O <sub>7-x</sub> target. <b>1995</b> , 265, 29-32		
501	Correlations between mean sputter depth and ion fluence during sputtering of binary component materials. <b>1995</b> , 46, 49-51		2
500	Contribution of kinetic emission to multicharged ion-induced electron emission from a metal surface. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1995</b> , 98, 450-453	1.2	2
499	Measurement of negative-ion and -cluster sputtering with highly-charged heavy ions. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1995</b> , 100, 47-54	1.2	8
498	Thermal and ion beam diffusion constants of Sb impurity implanted into <100> Ni single crystal. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1995</b> , 101, 388-393	1.2	
497	Sputtering of Cu thin films on Ru(0001) by Ne <sup>+</sup> ion bombardment. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1995</b> , 106, 55-59	1.2	
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495	Effect of bulk binding forces on energetic-ion-induced collision cascades: A combined simulational and analytical approach. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1995</b> , 103, 275-283	1.2	8
494	Temporal aspects of sputtering of TaC targets. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>1995</b> , 102, 272-276	1.2	1

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491	Three-dimensional Monte Carlo calculation of Ga <sup>+</sup> ion penetration in an a-Se <sub>75</sub> Ge <sub>25</sub> thin film. <b>1995</b> , 78, 5975-5980		5
490	Oxide growth, refractive index, and composition depth profiles of structures formed by 2 MeV oxygen implantation into silicon. <b>1995</b> , 77, 577-586		5
489	Monte Carlo Simulation of Ion Bombardment at Low Glancing Angles. <b>1995</b> , 34, 3303-3306		7
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271	Modeling of plasma-target interaction during reactive magnetron sputtering of TiN. <b>2007</b> , 102, 094501		32
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269	Computer Simulation of the Sputtering Process. <b>2007</b> , 21-31		10
268	Sputtering Yields. <b>2007</b> , 33-187		85
267	Results of Molecular Dynamics Calculations. <b>2007</b> , 189-230		14
266	Introduction and Overview. <b>2007</b> , 1-20		25
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181	Ion beam sputtering of Ag: Angular and energetic distributions of sputtered and scattered particles. <i>Nuclear Instruments &amp; Methods in Physics Research B</i> , <b>2013</b> , 316, 198-204	1.2	27
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134	The Phobos neutral and ionized torus. <b>2016</b> , 121, 770-783	7



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131	Method for ion beam etching in angles with multi-layers model. <b>2016</b> ,		
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